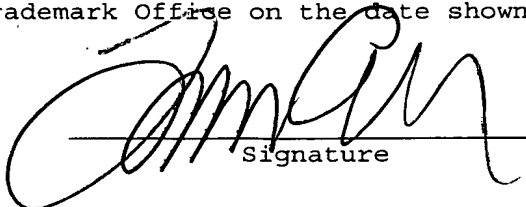


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CERTIFICATION OF MAILING OR TRANSMISSION

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SignatureJanuary 4, 2005
DateIN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/675,049 Confirmation No: 5871
Applicant : Ioannis Dotsikas
Filed : September 30, 2003
Title : METHOD AND FURNACE FOR THE VAPOR PHASE
DEPOSITION OF COMPONENTS ONTO SEMICONDUCTOR
SUBSTRATES WITH A VARIABLE MAIN FLOW DIRECTION
OF THE PROCESS GAS
Art Unit : 2818
Examiner : Renee R. Berry
Docket No. : MUH-12818
Customer No. : 24131

AMENDMENT

Hon. Commissioner for Patents
P.O. Box 1459
Alexandria, VA 22313-1450

S i r :

Responsive to the Office action dated October 4, 2004 kindly
amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of
claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.